

FIG. 1

METHOD OF MANUFACTURING SILICON CARBIDE FILM

Kiyoshi Satoh, et al.

Appl. No.: Unknown *Atty Docket: ASMJP.133CPI*

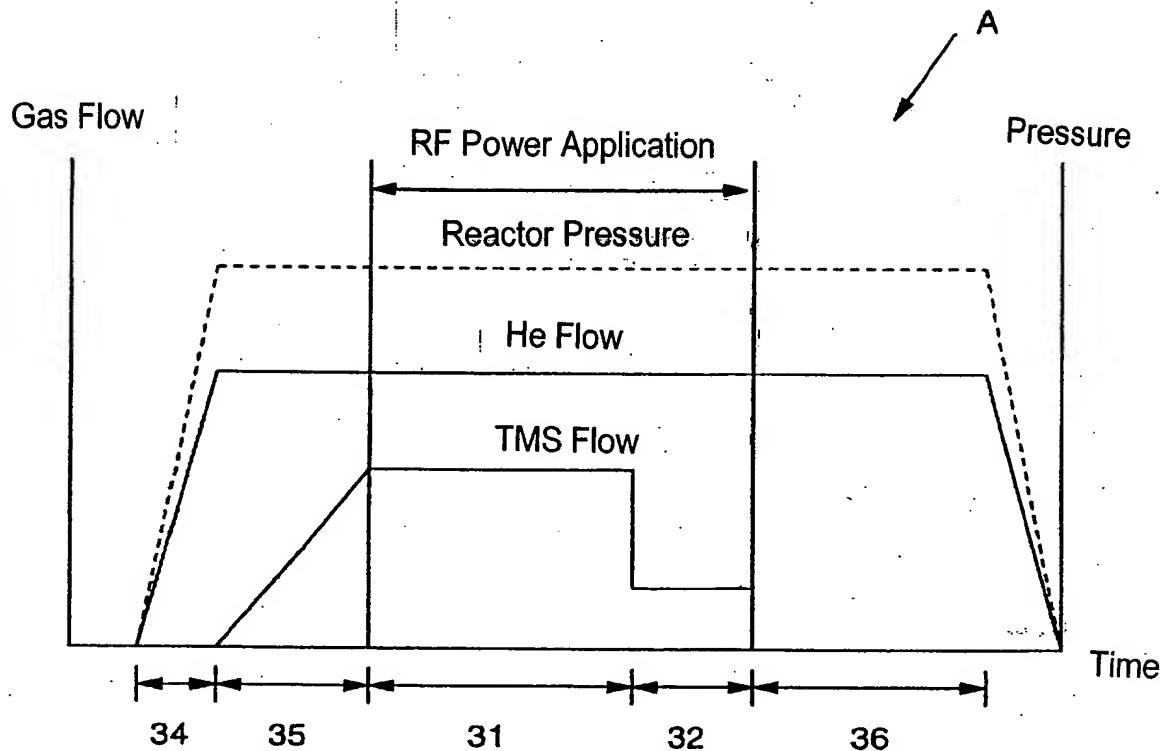


FIG. 2

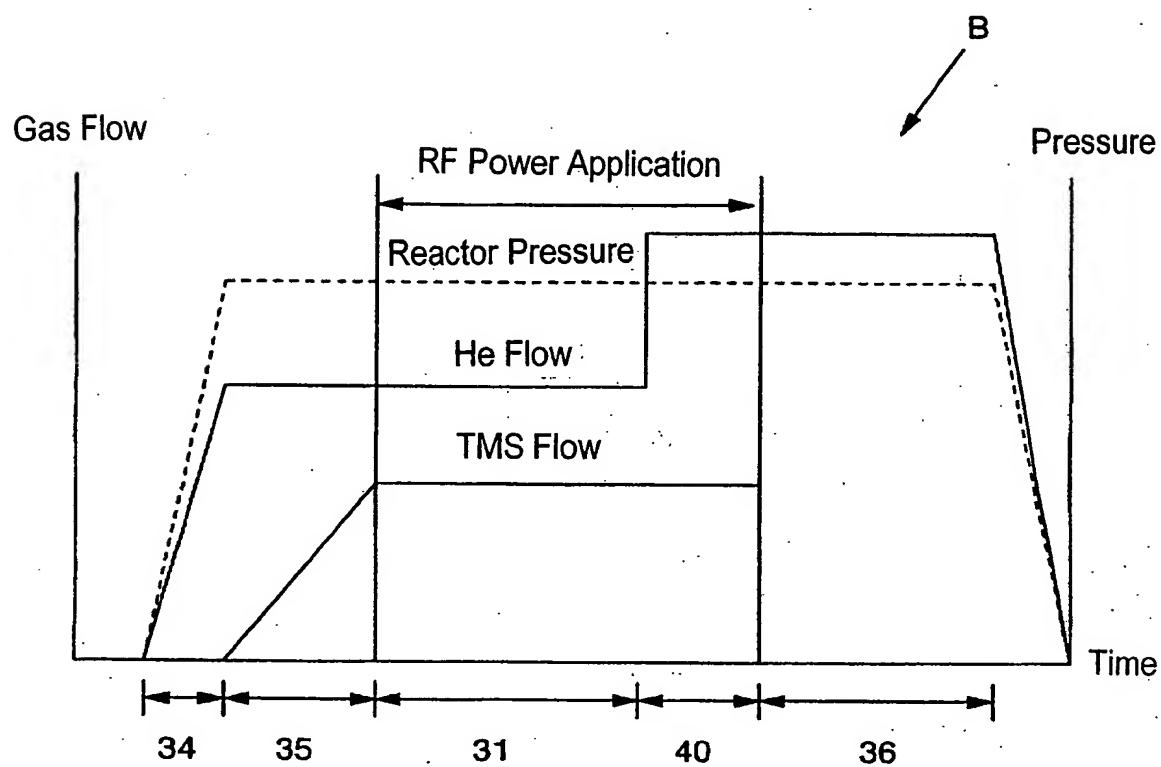


FIG. 3

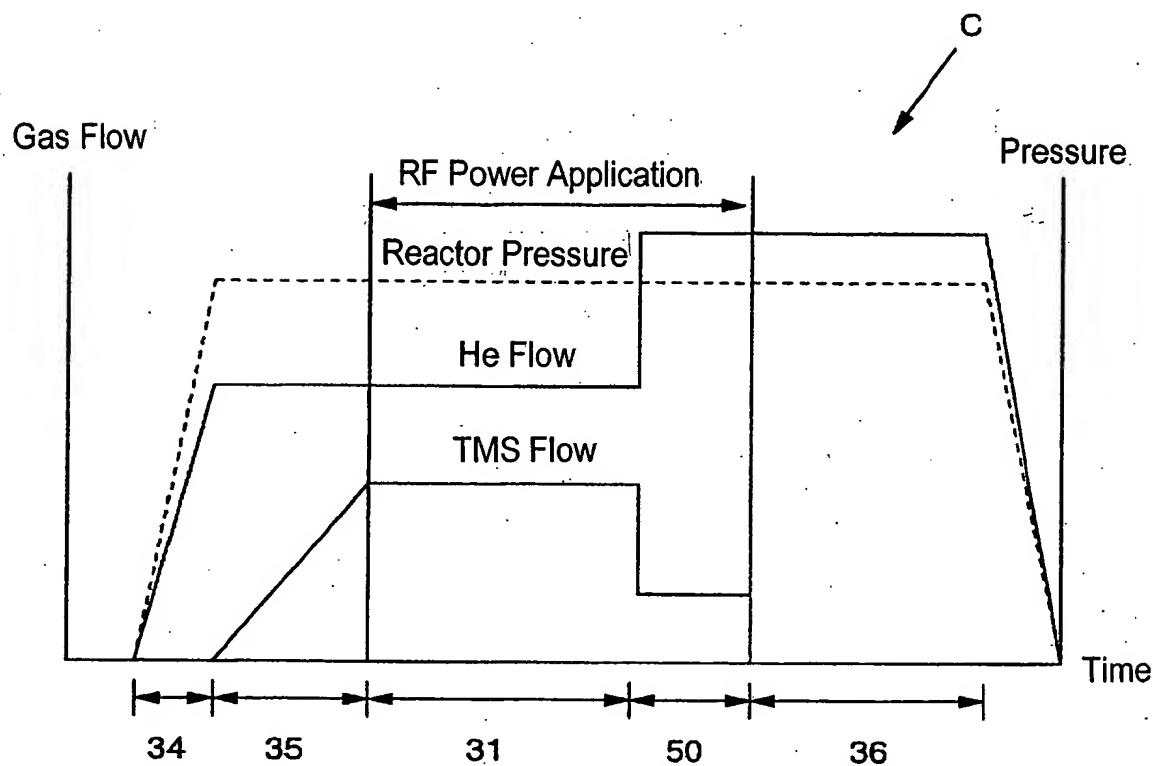


FIG. 4

METHOD OF MANUFACTURING SILICON CARBIDE FILM

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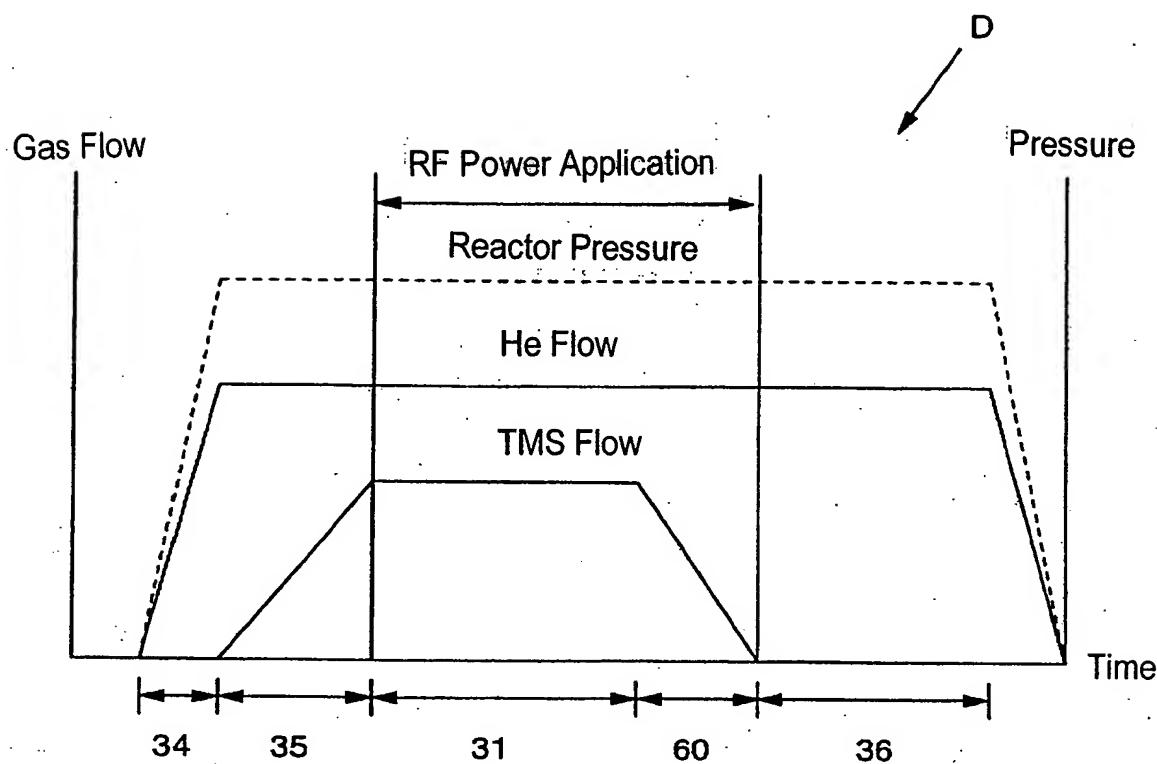


FIG. 5.

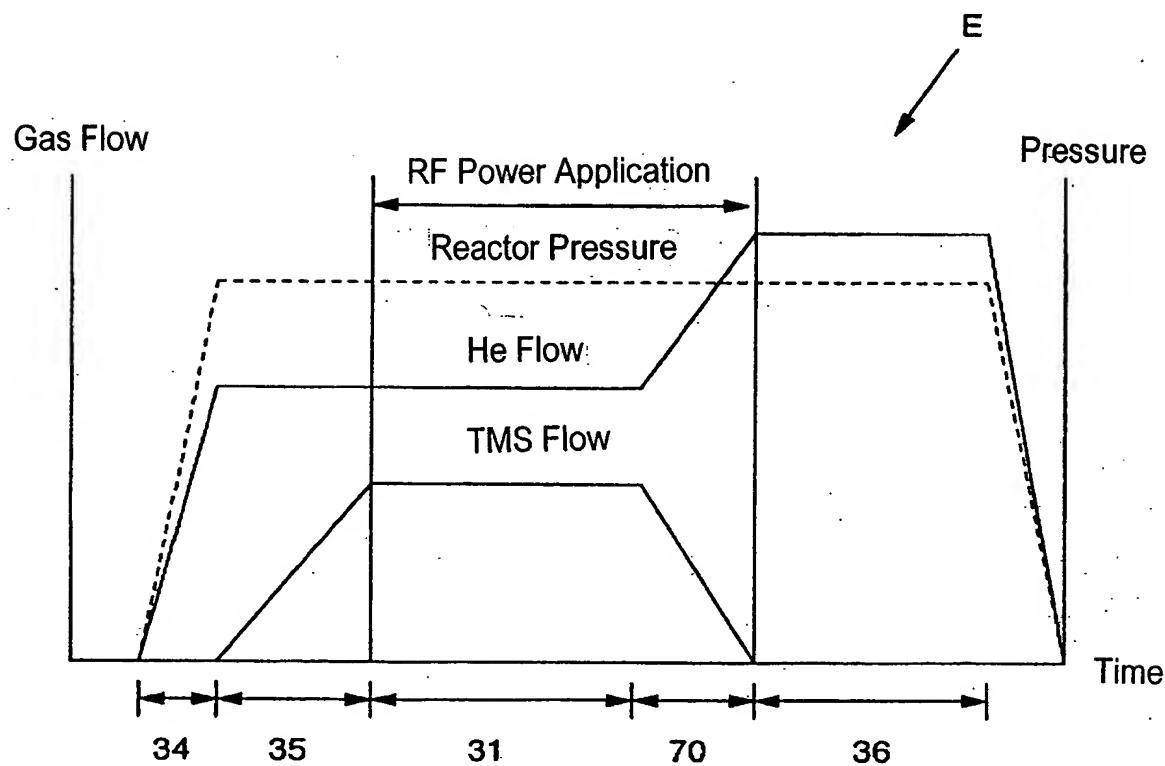


FIG. 6

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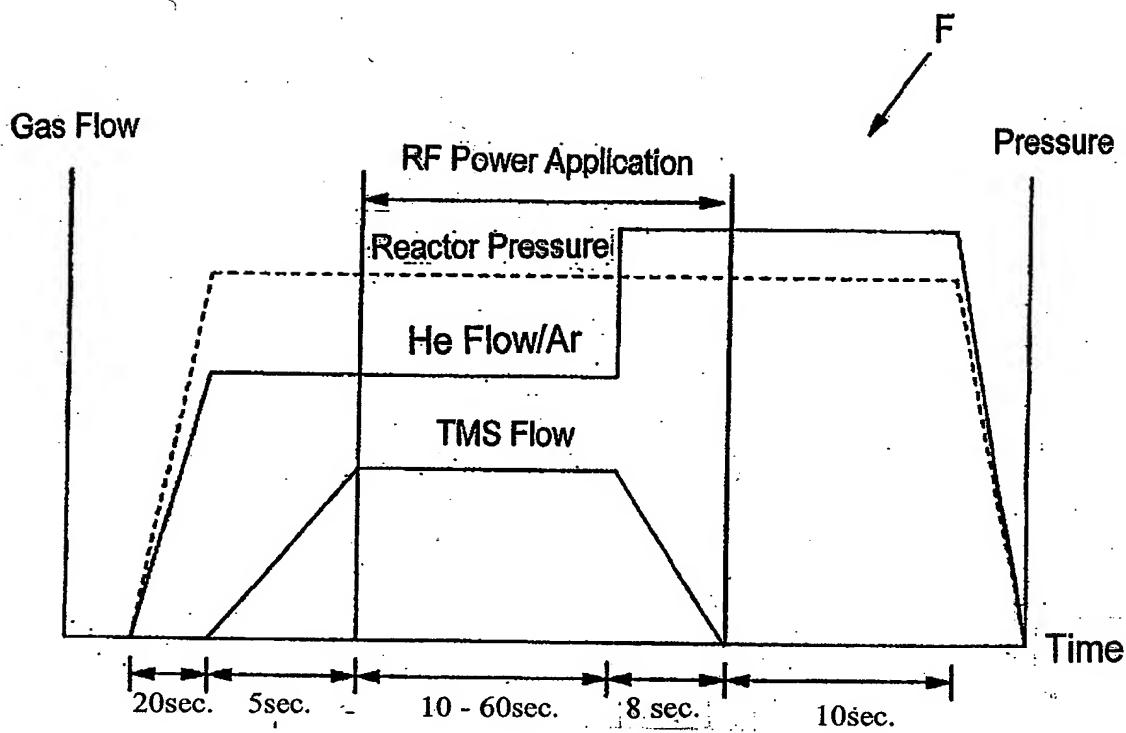


FIG. 7

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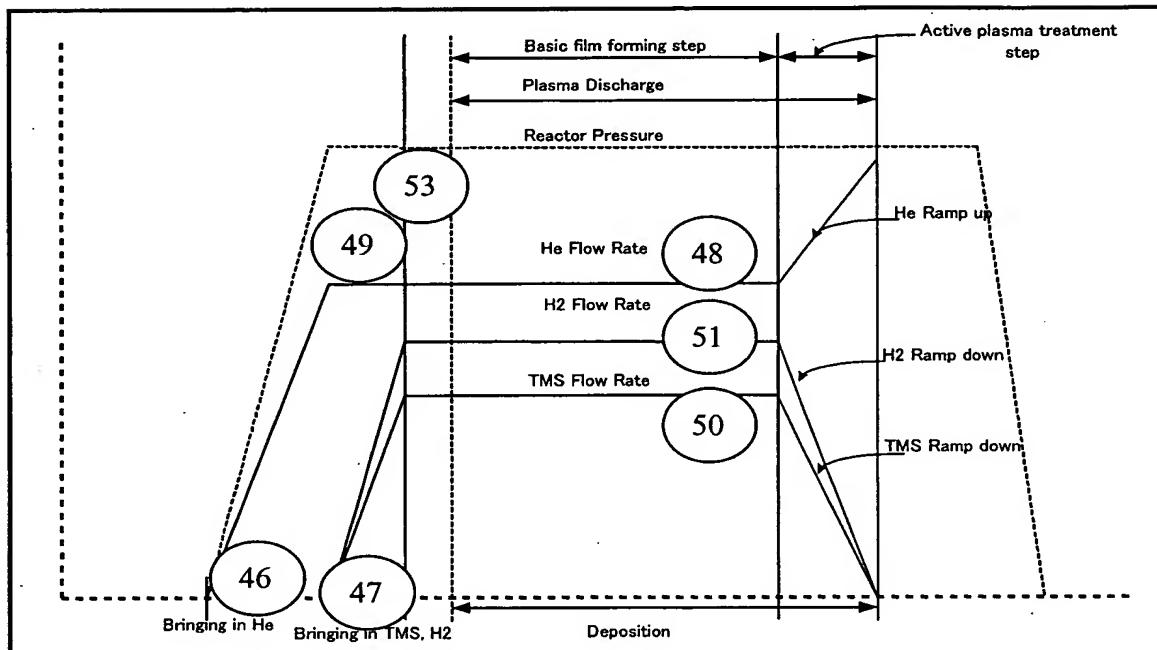


FIG. 8

FIG. 9a

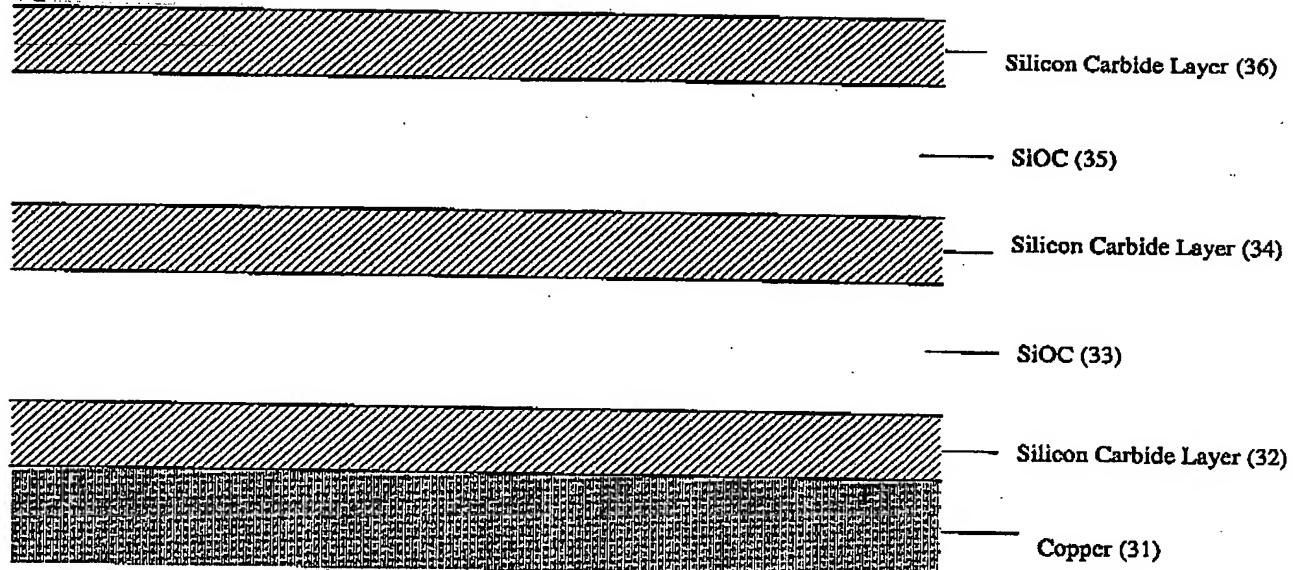
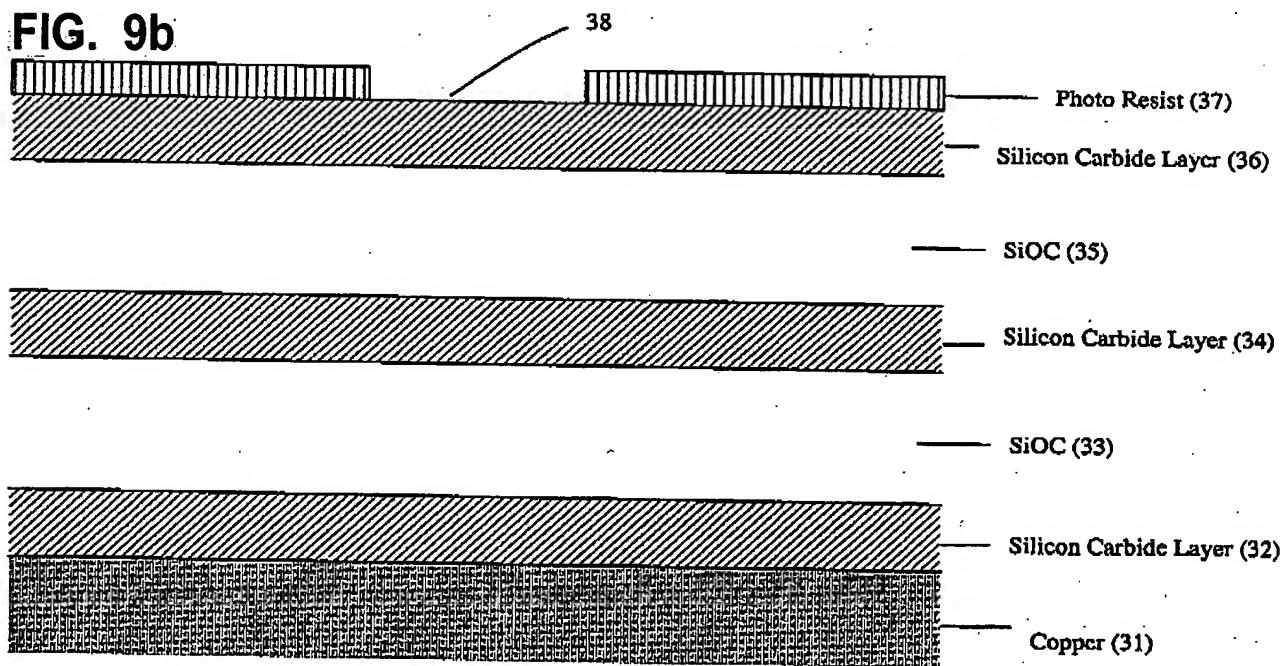


FIG. 9b



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FIG. 9c

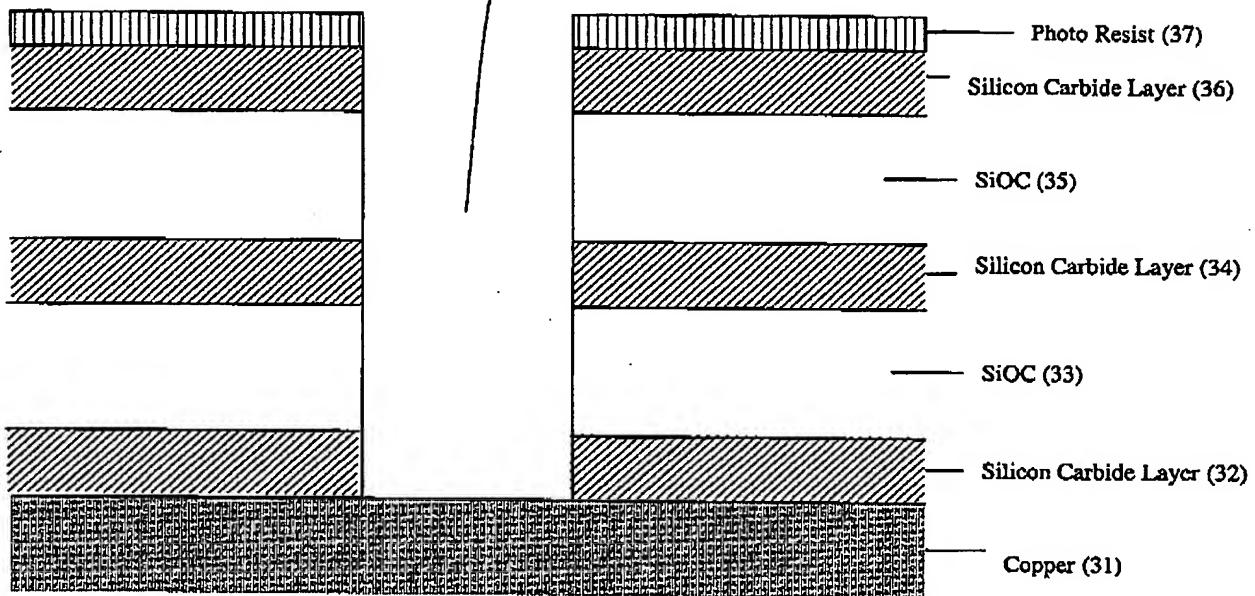
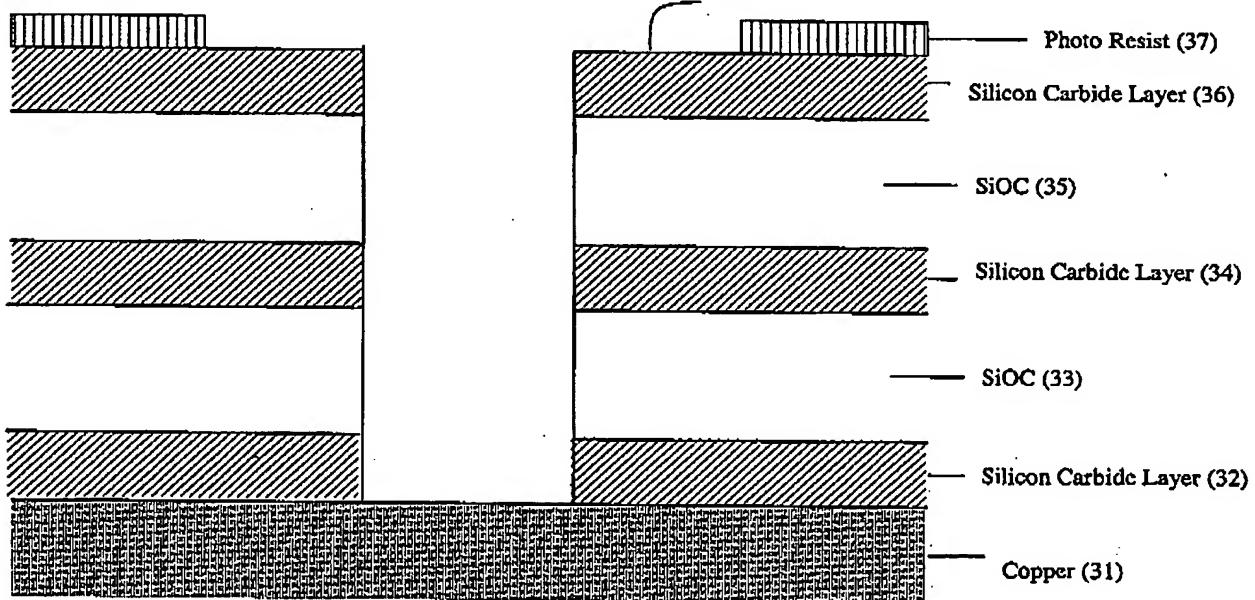


FIG. 9d



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FIG. 9e

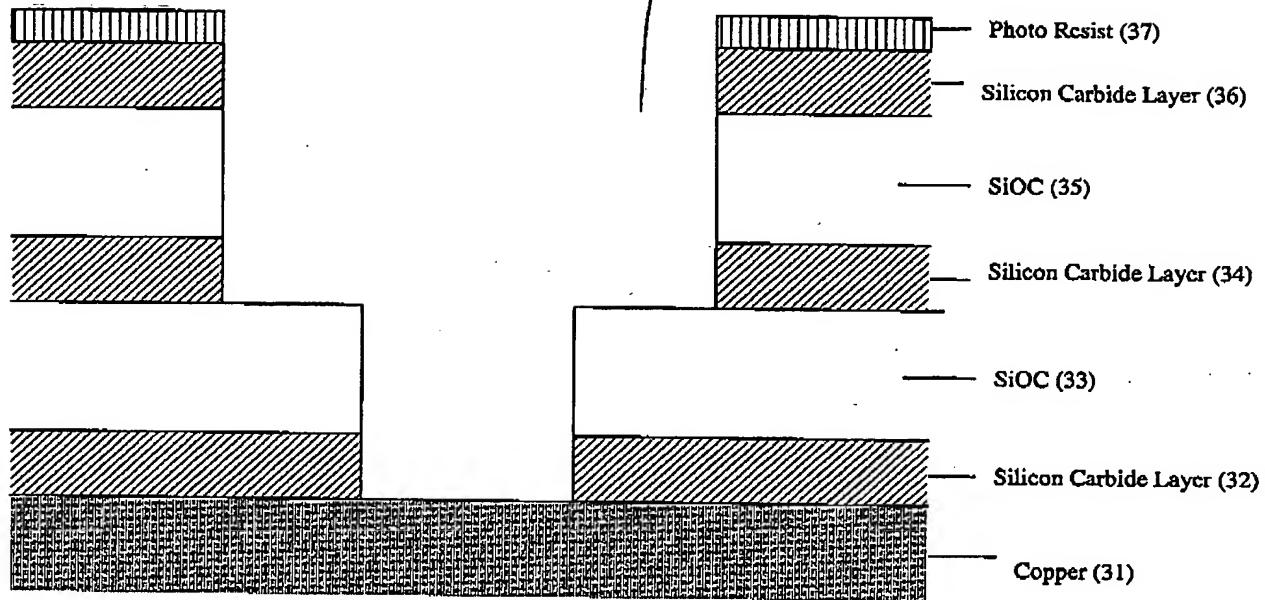
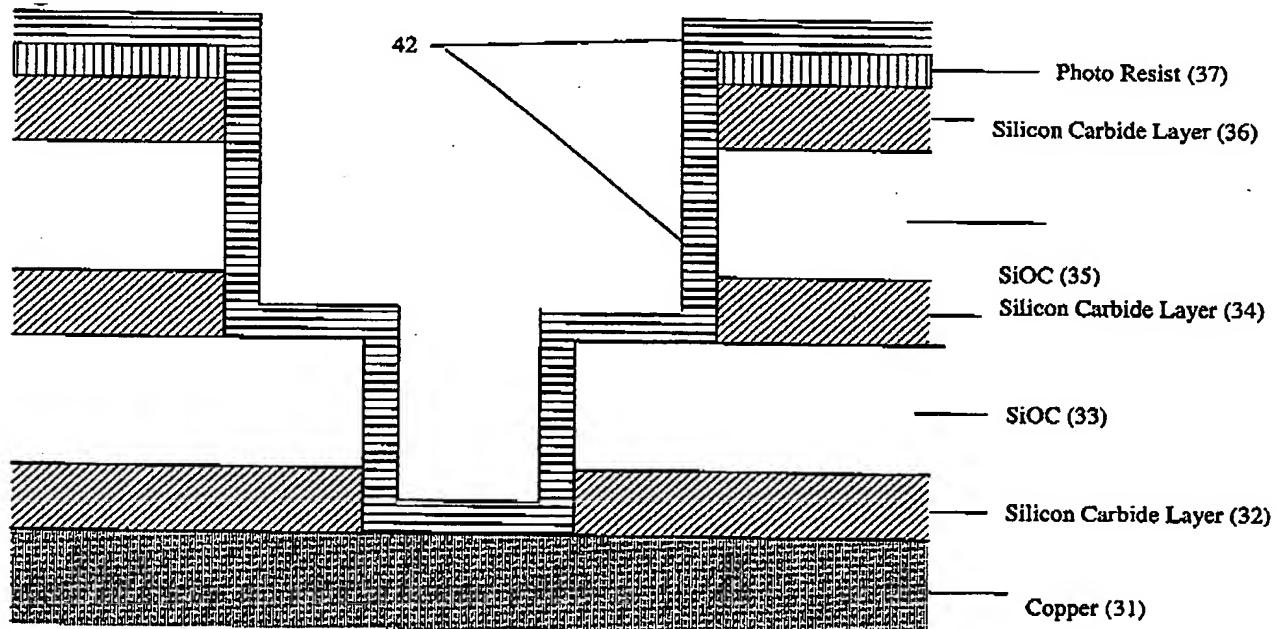


FIG. 9f



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FIG. 9g

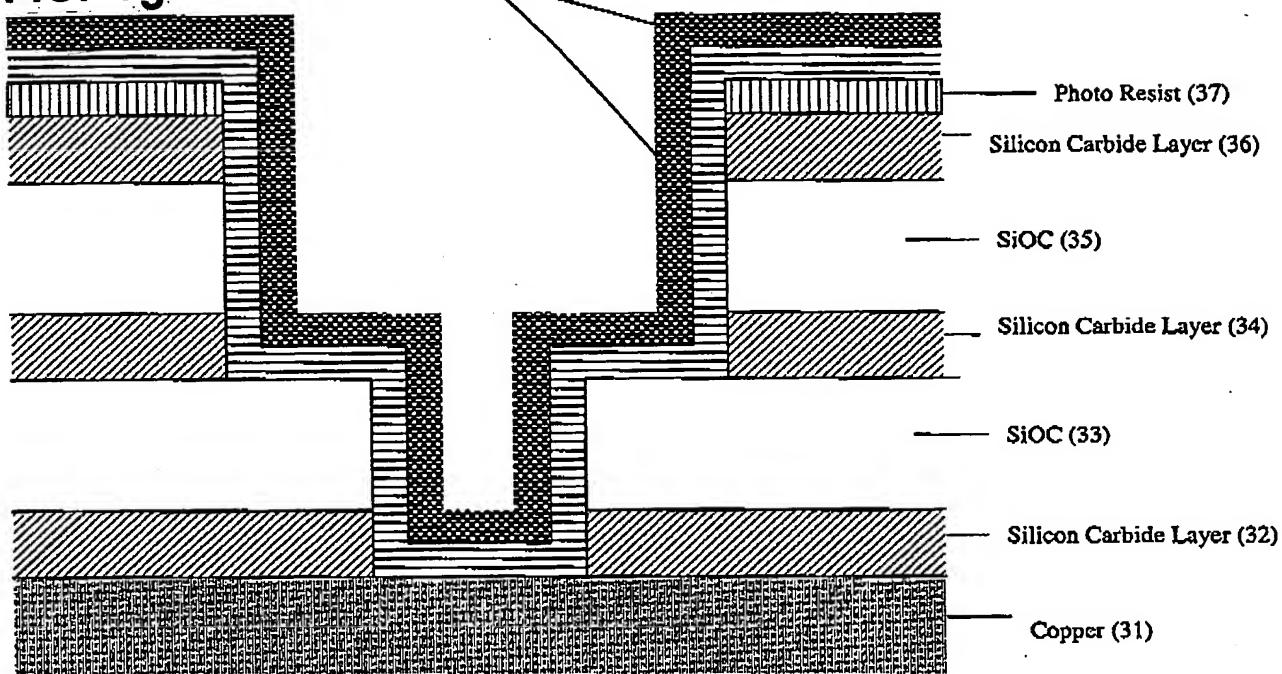


FIG. 9h

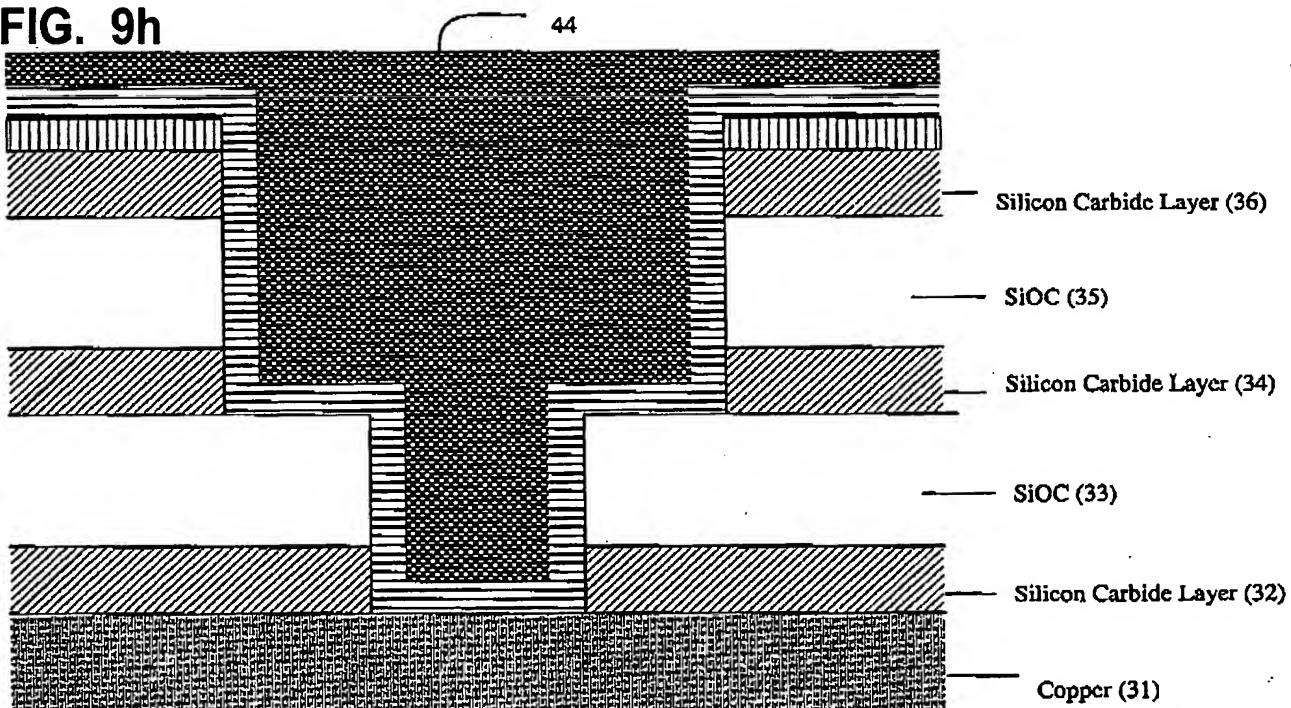


FIG. 9i

